



*OK to Enter*  
*2-10-2005*

[10191/1808]

**REPLY UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
GROUP ART UNIT 1763**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Inventor(s) : Franz LAERMER et al.  
Serial No. : 09/889,838  
Filed : January 24, 2002  
For : PLASMA ETCHING METHOD HAVING PULSED  
SUBSTRATE ELECTRODE POWER  
Examiner : Allan Olsen  
Art Unit : 1763  
Confirmation No. : 1541

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on:

Date: Jan. 20, 2005

Signature: *Chili*

**REPLY UNDER 37 C.F.R. § 1.116**

S I R:

In response to the Final Office Action of July 30, 2003, kindly amend the above-captioned application as follows:

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 7 of this paper.

01/26/2005 MAHME1 00000016 110600 09889838

01 FC:1253 1020.00 DA